

[IEEE HOME](#) | [SEARCH IEEE](#) | [SHOP](#) | [WEB ACCOUNT](#) | [CONTACT IEEE](#)



[Membership](#) | [Publications/Services](#) | [Standards](#) | [Conferences](#) | [Careers/Jobs](#)

IEEE Xplore
NEW! IEEE Xplore

Welcome
United States Patent and Trademark Office

[Help](#) | [FAQ](#) | [Terms](#) | [IEEE Peer Review](#)

[Quick Links](#)

» Search Results

Your search matched **2** of **987057** documents.
Results are shown **15** to a page, sorted by **publication year in descending order**.

Results:

Journal or Magazine = JNL Conference = CNF Standard = STD

1 In-line wafer inspection data warehouse for automated defect limited yield analysis

Iwata, H.; Ono, M.; Konishi, J.; Isogai, S.; Furutani, T.;

Advanced Semiconductor Manufacturing Conference and Workshop, 2000 IEEE/SEMI ,
12-14 Sept. 2000

Page(s): 124 -129

[Abstract] [PDF Full-Text (532 KB)] **IEEE CNF**

2 Optical fiber Ethernet data transmission

Kodera, H.; Asada, H.; Ikeda, H.; Yoshida, H.; Natsume, M.; Isogai, S.;

Industrial Automation and Control: Emerging Technologies, 1995., International
IEEE/IAS Conference on , 22-27 May 1995

Page(s): 657 -662

[Abstract] [PDF Full-Text (436 KB)] **IEEE CNF**

- Search**
- ☐ By Author
 - ☐ Basic
 - ☐ Advanced
- Member Services**
- ☐ Join IEEE
 - ☐ Establish IEEE Web Account
 - ☐ Access the IEEE Member Digital Library
- Print Format

[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#)
[Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#)
[No Robots Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)

Copyright © 2003 IEEE — All rights reserved